Docket No.: 0941-0759P

Application No.: 10/600,524

AMENDMENTS TO THE CLAIMS

1. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch

over the active region, and coupled to a first node;

a second gate disposed on a first side of the first gate and near the first end of the first

gate; and

a-first and second doping regions onat the first and a-second sides of the first gate, and

coupled to a second and the first node respectively, wherein the first doping region has a first

gap discontinuity region, without source/drain implantation, in the substrate under the second

gate.

2. (Original) The ESD protection device as claimed in claim 1, wherein the isolation

region is a shallow trench isolation.

3. (Original) The ESD protection device as claimed in claim 1, wherein the first node is

ground while the second node is a pad.

4. (Currently Amended) The ESD protection device as claimed in claim 1 further

3

comprising:

Docket No.: 0941-0759P

a third gate disposed on at the first side of the first gate and near the second end of the

first gate, wherein the first doping region has a second gapdiscontinuity region, without

source/drain implantation, in the substrate under the third gate.

5. (Currently Amended) The ESD protection device as claimed in claim 4 further

comprising:

a fourth gate having a first and second end overlapping the isolation region to stretch over

the active region, and coupled to the first node, wherein the first doping region is between the

first and fourth gate;

a fifth and sixth gate both disposed on-at a first side of the fourth gate, and respectively

near a first and second end of the fourth gate, wherein the first doping region has a third and

fourth gapdiscontinuity region, without source/drain implantation, respectively in the substrate

under the fifth and sixth gate; and

a third doping region on a second side of the fourth gate and coupled to the second node.

6. (Original) The ESD protection device as claimed in claim 5, wherein each of the

second, third, fifth and sixth gate has one end overlapping the isolation region.

7. (Original) The ESD protection device as claimed in claim 5, wherein each of the first,

second, third, fourth, fifth and sixth gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

4

Docket No.: 0941-0759P

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

8. (Original) The ESD protection device as claimed in claim 7, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

9. (Original) The ESD protection device as claimed in claim 1 further comprising a

fourth doping region enclosing the isolation region.

10. (Original) The ESD protection device as claimed in claim 9, wherein the substrate is

a P substrate, the first, second and third doping region are N doping regions, and the fourth

doping region is a P doping region.

11. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch

over the active region, and coupled to a first node;

a second gate disposed on a second side of the first gate and near the first end of the first

gate; and

5

Docket No.: 0941-0759P

a-first and second doping regions on at a the first and the second sides of the first gate,

and coupled to a second and the first node respectively, wherein the second doping region has a

first gap discontinuity region, without source/drain implantation, in the substrate under the second

gate.

12. (Original) The ESD protection device as claimed in claim 11, wherein the isolation

region is a shallow trench isolation.

13. (Original) The ESD protection device as claimed in claim 11, wherein the first node

is ground while the second node is a pad.

14. (Currently Amended) The ESD protection device as claimed in claim 11 further

comprising:

a third gate disposed on-at the second side of the first gate and near the second end of the

first gate, wherein the second doping region has a second gapdiscontinuity region, without

source/drain implantation, in the substrate under the third gate.

15. (Currently Amended) The ESD protection device as claimed in claim 14 further

comprising:

a fourth gate having a first and second end overlapping the isolation region to stretch over

the active region, and coupled to the first node, wherein the first doping region is between the

first and fourth gate;

6

Docket No.: 0941-0759P

a fifth and sixth gate both disposed on-at a first side of the fourth gate, and respectively

near a first and second end of the fourth gate; and

a third doping region on the first side of the fourth gate, coupled to the second node, and

having a third and fourth gapdiscontinuity region, without source/drain implatation, respectively

in the substrate under the fifth and sixth gate.

16. (Original) The ESD protection device as claimed in claim 15, wherein each of the

second, third, fifth and sixth gate has one end overlapping the isolation region.

17. (Original) The ESD protection device as claimed in claim 15, wherein each of the

first, second, third, fourth, fifth and sixth gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

18. (Original) The ESD protection device as claimed in claim 17, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

19. (Original) The ESD protection device as claimed in claim 11 further comprising a

7

fourth doping region enclosing the isolation region.

Docket No.: 0941-0759P

20. (Original) The ESD protection device as claimed in claim 19, wherein the substrate

is a P substrate, the first, second and third doping region are N doping regions, and the fourth

doping region is a P doping region.

21. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch

over the active region, and coupled to a first node; and

a-first and second doping regions on at the first and a-second sides of the first gate, and

coupled to a second and the first node respectively, wherein the first doping region has a first

gapdiscontinuity region near the first end of the first gate.

22. (Original) The ESD protection device as claimed in claim 21, wherein the isolation

region is a shallow trench isolation.

23. (Original) The ESD protection device as claimed in claim 21, wherein the first node

is ground while the second node is a pad.

Docket No.: 0941-0759P

24. (Currently Amended) The ESD protection device as claimed in claim 21, wherein the

first doping region further has a second gapdiscontinuity region near the second end of the first

gate.

25. (Currently Amended) The ESD protection device as claimed in claim 24 further

comprising:

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on a first

side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node;

wherein the first doping region has a third and fourth gapdiscontinuity region respectively

near the first and second end of the second gate.

26. (Currently Amended) The ESD protection device as claimed in claim 25, wherein

each of the first, second, third and fourth gapdiscontinuity region has one end connected to the

isolation region.

27. (Original) The ESD protection device as claimed in claim 26, wherein each of the

first and second gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

9

Docket No.: 0941-0759P

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

28. (Original) The ESD protection device as claimed in claim 27, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

29. (Original) The ESD protection device as claimed in claim 21 further comprising a

fourth doping region enclosing the isolation region.

30. (Original) The ESD protection device as claimed in claim 29, wherein the substrate

is a P substrate, the first, second and third doping region are N doping regions, and the fourth

doping region is a P doping region.

31. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and secondtwo ends overlapping the isolation region to stretch

over the active region, and coupled to a first node; and

a-first and second doping regions on at the first and a-second sides of the first gate, and

coupled to a second and the first node respectively, wherein the second doping region has a first

gapdiscontinuity region near the first end of the first gate.

KM/asc

10

Docket No.: 0941-0759P

32. (Original) The ESD protection device as claimed in claim 31, wherein the isolation

region is a shallow trench isolation.

33. (Original) The ESD protection device as claimed in claim 31, wherein the first node

is ground while the second node is a pad.

34. (Original) The ESD protection device as claimed in claim 31, wherein the second

doping region further has a second gapdiscontinuity region near the second end of the first gate.

35. (Currently Amended) The ESD protection device as claimed in claim 34 further

comprising:

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on at a

first side of the second gate; and

a third doping region on at a second side of the second gate, coupled to the second node;

wherein the second doping region has a third and fourth gapdiscontinuity region

respectively near the first and second end of the second gate.

36. (Currently Amended) The ESD protection device as claimed in claim 35, wherein

each of the first, second, third and fourth gapdiscontinuity regions has one end connected to the

isolation region.

11

Docket No.: 0941-0759P

37. (Original) The ESD protection device as claimed in claim 36, wherein each of the first and second gates comprises:

38. (Original) The ESD protection device as claimed in claim 37, wherein the conducting layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon oxide layers.

- 39. (Original) The ESD protection device as claimed in claim 31 further comprising a fourth doping region enclosing the isolation region.
- 40. (Original) The ESD protection device as claimed in claim 39, wherein the substrate is a P substrate, the first, second and third doping region are N doping regions, and the fourth doping region is a P doping region.
 - 41. (Currently Amended) An ESD protection device comprising:
 - a substrate;
 - an isolation region on the substrate, enclosing an active region;
- a first gate having a first and second two ends overlapping the isolation region to stretch over the active region, and coupled to a first node; and
- a-first and second doping regions on at the first and a-second sides of the first gate, and coupled to a second and the first node respectively;

Docket No.: 0941-0759P

wherein the isolation region protruding into the first doping region near the first end of the first gate.

- 42. (Original) The ESD protection device as claimed in claim 41, wherein the isolation region is a shallow trench isolation.
- 43. (Original) The ESD protection device as claimed in claim 41, wherein the first πode is ground while the second node is a pad.
- 44. (Original) The ESD protection device as claimed in claim 41, wherein the isolation region protruding into the first doping region near the second end of the first gate.
 - 45. (Original) The ESD protection device as claimed in claim 44 further comprising:
- a second gate having a first and second end overlapping the isolation region to stretch over the active region, and coupled to the first node, wherein the first doping region is on a first side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node;

wherein the isolation region protruding into the first doping region near the first and second end of the second gate.

46. (Original) The ESD protection device as claimed in claim 45, wherein each of the first and second gate comprises:

13

Docket No.: 0941-0759P

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

47. (Original) The ESD protection device as claimed in claim 46, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

48. (Original) The ESD protection device as claimed in claim 41 further comprising a

fourth doping region enclosing the isolation region.

49. (Original) The ESD protection device as claimed in claim 48, wherein the substrate

is a P substrate, the first, second and third doping regions are N doping regions, and the fourth

doping region is a P doping region.

50. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and secondiwo ends overlapping the isolation region to stretch

over the active region, and coupled to a first node; and

Docket No.: 0941-0759P

a-first and second doping regions on at the first and a second sides of the first gate, and coupled to a second and the first node respectively;

wherein the isolation region protruding into the second doping region near the first end of the first gate.

- 51. (Original) The ESD protection device as claimed in claim 50, wherein the isolation region is a shallow trench isolation.
- 52. (Original) The ESD protection device as claimed in claim 50, wherein the first node is ground while the second node is a pad.
- 53. (Original) The ESD protection device as claimed in claim 50, wherein the isolation region protruding into the second doping region near the second end of the first gate.
 - 54. (Original) The ESD protection device as claimed in claim 53 further comprising:

a second gate having a first and second end overlapping the isolation region to stretch over the active region, and coupled to the first node, wherein the first doping region is on a first side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node;

wherein the isolation region protruding into the second doping region near the first and
second end of the second gate.

15

Docket No.: 0941-0759P

55. (Original) The ESD protection device as claimed in claim 54, wherein each of the

first and second gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

56. (Original) The ESD protection device as claimed in claim 55, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

57. (Original) The ESD protection device as claimed in claim 50 further comprising a

fourth doping region enclosing the isolation region.

58. (Original) The ESD protection device as claimed in claim 57, wherein the substrate

is a P substrate, the first, second and third doping regions are N doping regions, and the fourth

doping region is a P doping region.

59. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

16

Docket No.: 0941-0759P

a first gate having a first and second two ends overlapping the isolation region to stretch

over the active region, and coupled to a first node; and

a-first and second doping regions on at the first and a second sides of the first gate, and

coupled to a second and the first node respectively;

wherein the isolation region has a first portion under the first end of the first gate

protruding into both the first and second doping region.

60. (Original) The ESD protection device as claimed in claim 59, wherein the isolation

region is a shallow trench isolation.

61. (Original) The ESD protection device as claimed in claim 59, wherein the first node

is ground while the second node is a pad.

62. (Original) The ESD protection device as claimed in claim 59, wherein the isolation

region further has a second portion under the second end of the first gate protruding into both the

first and second doping regions.

63. (Original) The ESD protection device as claimed in claim 62 further comprising:

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on a first

side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node;

17

Docket No.: 0941-0759P

wherein the isolation region has a third and fourth portion respectively under the first and

second protruding into both the first and second doping region.

64. (Original) The ESD protection device as claimed in claim 63, wherein each of the

first and second gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

65. (Original) The ESD protection device as claimed in claim 64, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

66. (Original) The ESD protection device as claimed in claim 59 further comprising a

fourth doping region enclosing the isolation region.

67. (Original) The ESD protection device as claimed in claim 66, wherein the substrate

is a P substrate, the first, second and third doping region are N doping regions, and the fourth

doping region is a P doping region.

68. (Original) An ESD protection device comprising:

Docket No.: 0941-0759P

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch over the active region, and coupled to a first node;

a first and second doping region on the first and a second side of the first gate, and coupled to a second and the first node respectively; and

a third doping region disposed under the first and second doping regions and near the first end of the first gate, having a doping concentration lower than that of the first and second doping regions.

- 69. (Original) The ESD protection device as claimed in claim 68, wherein the isolation region is a shallow trench isolation.
- 70. (Original) The ESD protection device as claimed in claim 68, wherein the first node is ground while the second node is a pad.
- 71. (Original) The ESD protection device as claimed in claim 68 further comprising a fourth doping region disposed under the first and second doping regions and near the second end of the first gate, having a doping concentration lower than that of the first and second doping regions.
 - 72. (Original) The ESD protection device as claimed in claim 71 further comprising:

Docket No.: 0941-0759P

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on a first

side of the second gate; and

a fifth doping region on a second side of the second gate, coupled to the second node;

wherein the third doping region is disposed under the first, second and fifth doping

regions and near the first end of the first and second gate while the fourth doping region is

disposed under the first, second and fifth doping regions and near the second end of the first and

second gates.

73. (Original) The ESD protection device as claimed in claim 72, wherein each of the

first and second gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

74. (Original) The ESD protection device as claimed in claim 73, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

75. (Original) The ESD protection device as claimed in claim 68 further comprising a

sixth doping region enclosing the isolation region.

Docket No.: 0941-0759P

76. (Original) The ESD protection device as claimed in claim 75, wherein the substrate is a P substrate, the first, second, third, fourth and fifth doping region are N doping regions, and the sixth doping region is a P doping region.

77. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch over the active region, and coupled to a first node;

a-first and second doping regions en at the first and a second sides of the first gate, and coupled to a second and the first node respectively; and

a first doping region well disposed under the first doping region and near the first end of the first gate.

- 78. (Original) The ESD protection device as claimed in claim 77, wherein the isolation region is a shallow trench isolation.
- 79. (Original) The ESD protection device as claimed in claim 77, wherein the first node is ground while the second node is a pad.

Docket No.: 0941-0759P

80. (Original) The ESD protection device as claimed in claim 77 further comprising a second doping region well disposed under the first doping region and near the second end of the

first gate.

81. (Original) The ESD protection device as claimed in claim 80 further comprising:

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on a first

side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node.

82. (Original) The ESD protection device as claimed in claim 81, wherein each of the

first and second gates comprise:

a conducting layer;

a gate oxide layer under the conducting layer, and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

83. (Original) The ESD protection device as claimed in claim 82, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

22

Docket No.: 0941-0759P

84. (Original) The ESD protection device as claimed in claim 77 further comprising a

fourth doping region enclosing the isolation region.

85. (Original) The ESD protection device as claimed in claim 84, wherein the substrate

is a P substrate, the first, second and third doping regions are N doping regions, and the first and

second doping regions are P doping regions.

86. (Currently Amended) An ESD protection device comprising:

a substrate;

an isolation region on the substrate, enclosing an active region;

a first gate having a first and second two ends overlapping the isolation region to stretch

over the active region, and coupled to a first node; and

a first and second doping region on the first and a second side of the first gate, and

coupled to a second and the first node respectively; and

wherein the first gate protruding into the first doping region so that, in the first doping

region, a width of a center portion is larger than those of portions near the first and second end of

the first gate.

87. (Original) The ESD protection device as claimed in claim 86, wherein the isolation

region is a shallow trench isolation.

Docket No.: 0941-0759P

88. (Original) The ESD protection device as claimed in claim 86, wherein the first node

is ground while the second node is a pad.

89. (Original) The ESD protection device as claimed in claim 86 further comprising:

a second gate having a first and second end overlapping the isolation region to stretch

over the active region, and coupled to the first node, wherein the first doping region is on a first

side of the second gate; and

a third doping region on a second side of the second gate, coupled to the second node;

wherein the second gate protruding into the first doping region.

90. (Original) The ESD protection device as claimed in claim 89, wherein each of the

first and second gate comprises:

a conducting layer;

a gate oxide layer under the conducting layer; and

a first and second spacer respectively adjacent to two sides of the conducting layer and

gate oxide layer.

91. (Original) The ESD protection device as claimed in claim 90, wherein the conducting

layer is a polysilicon layer while the gate oxide layer, and the first and second spacer are silicon

oxide layers.

P. 30

Application No.: 10/600,524

Docket No.: 0941-0759P

92. (Original) The ESD protection device as claimed in claim 86 further comprising a

fourth doping region enclosing the isolation region.

93. (Original) The ESD protection device as claimed in claim 92, wherein the substrate

is a P substrate, the first, second and third doping region are N doping regions, and the fourth

doping region is a P doping region.

94-103. (Cancelled)